IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Applic	cation of:		
Varun Singh, et al.		§ §	
	O ,	§	Previous Examiner: H. Tsai
Serial No.:	Not Assigned	§	
		§	Previous Group Art Unit: 2812
Filed:	Herewith	§	
		§	

For:

AN IMPROVED POLYSILICON RESISTOR HAVING ADJUSTABLE

TEMPERATURE COEFFICIENTS AND THE METHOD OF MAKING THE

SAME

BOX: Patent Application **Assistant Commissioner For Patents** Washington, D.C. 20231

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Joy L. Mowery

Dear Sir:

PRELIMINARY AMENDMENT

Signature

Prior to the examination of the above-identified application, please amend this application as follows:

IN THE CLAIMS

Please cancel Claims 3-10 and 13-15. Claims 1-2 and 11-12 remain for consideration in this application.

1. A resistor having a resistance that can be adjusted by current being passed there through and which is formed as part of a semiconductor device comprising:

a polycrystalline silicon resistor formed of on a layer, wherein said polysilicon resistor is formed using a doping wherein said doping has a concentration of from $\sim 6 \times 10^{19}$ cm⁻³ to $\sim 3.75 \times 10^{20}$ cm⁻³.

2. A resistor having a resistance that can be adjusted by current being passed there through and which is formed as part of a semiconductor device comprising:

a polycrystalline silicon resistor formed of on a layer, wherein said polysilicon resistor is formed using a doping wherein said doping has a concentration of less than $\sim 3.75 \times 10^{20}$ cm⁻³.

11. A resistor having a resistance that can be adjusted by current being passed there through and which is formed as part of a semiconductor device comprising:

a polycrystalline silicon resistor formed of on a layer, wherein said polysilicon resistor is formed using a doping wherein said doping has a concentration of greater than $\sim 6 \times 10^{19}$ cm⁻³.

12. A resistor having a resistance that can be adjusted by current being passed there through and which is formed as part of a semiconductor device comprising:

a polycrystalline silicon resistor formed of on a layer, wherein said polysilicon resistor is formed using a late implant doping technique.

REMARKS

In view of the above, it is believed that this application is in condition for allowance, and such a Notice is respectfully requested.

Respectfully submitted,

JENKENS & GILCHRIST A Professional Corporation

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